

**ECM 98: PRESIDENT'S REPORT**

There was a long period from the last meeting in Lanzarote (7 months). During this period there was a continuous activity in my office. There had been exchange of e-mails with Officers, Division and Committee Chairs and Councillors. The invitation to attend the ECM98 was mailed on 19<sup>th</sup> August 2005 . In particular I have sent a letter to Prof. Bhatti explaining the results of the discussion we had in the Education Committee.

During this period the activity of the Union was mainly devoted to organizing the activity for the triennium and to the preparation of the ECM 98. I would like to address your attention to the series of IUVSTA Conferences held in this period; the first was the 9<sup>th</sup> European Vacuum Congress EVC 9 held in Paris in April, a traditional meeting for the scientist and engineers working in the area of vacuum science and technology. The meeting was held in conjunction with the Vacuum Exhibition *Vide 2005* organised by the Manufacturer Committee of the French Vacuum Society (SFV), and with the celebration of the 60th anniversary of the SFV, the oldest vacuum society and a founder member of the Union. In June, the 13<sup>th</sup> International Congress on Thin Films (ICTF 13) was held in Stockholm together with the 8<sup>th</sup> Atomically Controlled Surfaces Interfaces and Nanostructures ACSIN. The conference was in the Congress Centre of the city of Stockholm, the same location where IVC-ICSS will be held in 2007. In July VASSCAA 3<sup>rd</sup> was organized in Singapore and in September in Berlin there was the annual symposium of the surface scientists ECOSS which is now at its 23<sup>rd</sup> edition. All these events, prepared and successfully organized by IUVSTA Divisions and by its member Societies show that IUVSTA plays a key role at the international level by bringing all different types of scientists, engineers and technologists together to discuss issues of common interest and promote the use and development of vacuum in science and technology.

I attended the Conference RIVA V - 5th Iberian Vacuum Meeting, Univ. do Minho, Guimarães, Portugal, Sept. 18<sup>th</sup> 21<sup>st</sup>, 2005. The Conference, co-organized by the Spanish Vacuum Society and by The Portuguese Vacuum society, had large attendance from the country area as well from Europe. The program was focused on thin films, vacuum and surfaces.

I attended the meeting "Towards future electronics: from fundamentals to nanodevices" held in Beijing from 28<sup>th</sup> September to October 1<sup>st</sup> 2005. The Conference was run together with the International Conference on Future of Information Technology. It was organized by the Nanometer structure division of the China Vacuum Society which is very active in that part of the world.

I had correspondence with T. Madey, and M. Ono concerning the donation programme. In particular, after the donation of Kratos Analytical, the IUVESTA received a new donation from the Funai Electric Advanced Applied Technology Research Institute Inc. (FEAT). I am very grateful to the President of FEAT, Dr. Tadashi Sasaki, for that contribution which increases the donation fund.

I met in Stockholm Prof. Moshfegh, President of the Iran Vacuum Society. We had a long conversation concerning the interest of the Iran Vacuum Society in joining IUVESTA. I have invited Prof. Moshfegh to attend ECM98 as an observer and to give a short description of the society during the Any Other Business item in the agenda. The application of the Iran Vacuum Society was received on 22<sup>nd</sup> September 2005 by me and I have transferred the message and the relative documentation to the Secretary General. The provisional admission of the Iran Vacuum Society to the Union will be in the ECM 99 agenda. If approved Iranian representatives will be admitted from ECM100.

In Beijing I had a conversation with Prof Ningsheng Xu from Canton University. He is member of the Board of the IVNC, International Vacuum Nanoelectronics Conference, and of the IFES, International Field Emission Symposium. He told me that the Committee have expressed interest in organizing these conferences in collaboration with IUVESTA. We will see the future outcomes. There is an Association that groups these Conferences and we can make an agreement with them.

The October 2005 issue of Physics World, the international magazine for members of the Institute of Physics, will include articles and case-studies covering the breadth of vacuum technology that physicists and engineers use for their work in both industry and academia. I contributed writing the article "Vacuum around the world". The paper describes the role of the International Union for Vacuum Science, Technique and Applications at the international level and illustrates its activities.

I have invited Prof. Manfred Leisch to attend this meeting as observer and to give, during this meeting, a presentation of the activities of the Austrian Vacuum Society.